Claims

| 1 | 1. A method for reworking an electronic component with copper or copper/nickel |
|---|---|
| 2 | pads containing a nickel layer and an overlying gold layer comprising the steps of: |
| 3 | supplying an electronic component having copper or copper/nickel pads thereon |
| 4 | containing a nickel layer and an overlying gold layer; |
| 5 | etching the gold layer on the component pads; |
| 6 | etching the nickel layer on the component pads; |
| 7 | treating the etched component to remove products formed during the etching steps |
| 8 | and corrosion products; and |
| 9 | plating the restored copper surface with a nickel layer followed by a gold layer. |

- 1 2. The method of claim 1 wherein the pads on the treated component are restored to their original condition by media blasting.
- 1 3. The method of claim 2 wherein the gold layer is etched using a cyanide containing solution.
- 1 4. The method of claim 3 wherein the nickel layer is etched using an alkaline oxidizer containing solution having a pH greater than about 12.0.
- 5. The method of claim 4 wherein the etched component is treated using a cyanide containing solution.
- 6. An apparatus for reworking an electronic component with copper or copper/nickel pads containing a nickel layer and an overlying gold layer comprising:

- supplying means to supply an electronic component having copper or copper/nickel pads thereon containing a nickel layer and an overlying gold layer;
- 5 etching means to etch the gold layer on the component pads;
- 6 etching means to etch the nickel layer on the component pads;
- treating means to remove products formed during the etching steps and corrosion products from the etched component; and
- 9 plating means to plate the restored copper or copper/nickel pad surface with a nickel layer and an overlying gold layer.
- 7. The apparatus of claim 6 wherein the pads on the treated component are restored to their original condition by media blasting.
- 1 8. The apparatus of claim 7 wherein the gold layer etching means is a cyanide containing solution.
- 1 9. The apparatus of claim 8 wherein the nickel layer etching means is an alkaline oxidizer containing solution having a pH greater than about 12.0.
- 1 10. The apparatus of claim 9 wherein the treating means is a cyanide containing solution.
- 1 11. A reworked electronic component made using the method of claim 1.
- 1 12. A reworked electronic component made using the method of claim 2.
- 1 13. A reworked electronic component made using the method of claim 3.

- 1 14. A reworked electronic component made using the method of claim 4.
- 1 15. A reworked electronic component made using the method of claim 5.